plate.

[0006a]

A nozzle of another embodiment comprises a header pipe to which a gas-dissolved liquid is supplied; a plurality of fine bubble generation nozzles for generating and discharging a liquid containing fine bubbles from the gas-dissolved liquid supplied from the header pipe; and a rectifier means that is provided with a slit and discharges the liquid discharged from the fine bubble generation nozzle from the slit.

[0007]

A substrate cleaning device of one embodiment includes the nozzle described above.

BRIEF DESCRIPTION OF DRAWINGS

[0008]

FIG. 1A is a schematic configuration diagram of a substrate cleaning device according to a first embodiment.

FIG. 1B is a schematic perspective view of a nozzle according to the first embodiment.

FIG. 2A is a schematic perspective view of the nozzle 1 when the piping 4 is removed.

FIG. 2B is an arrow view viewed from an arrow A1 in FIG. 2A.

FIG. 2C is a cross-sectional view of the longitudinal section B in FIG. 2A.

FIG. 2D is a longitudinal sectional view of a first modification of the first embodiment.

FIG. 2E is a longitudinal sectional view of a second modification of the first embodiment.

FIG. 2F is a schematic view illustrating a process of assembling a part of the nozzle 1a2 according to the second modification of the first embodiment when the spacers 184b and 194b are separate bodies.

FIG. 2G is a schematic view illustrating a process of assembling a part of the nozzle 1a2 according to the second